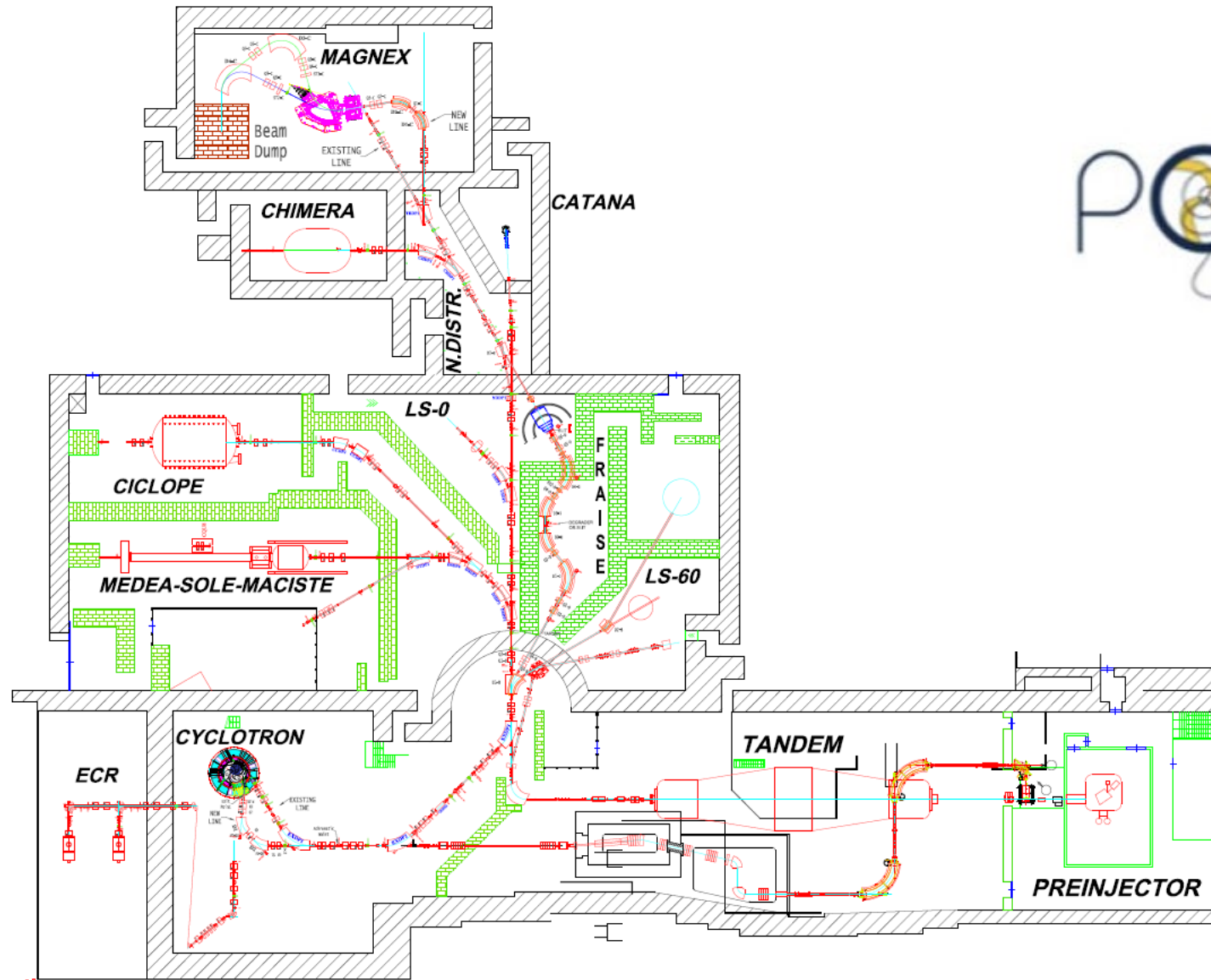


Accelerator's activities and perspectives at LNS

Luigi Celona

INFN-LNS Users Annual Meeting

December 19th 2022



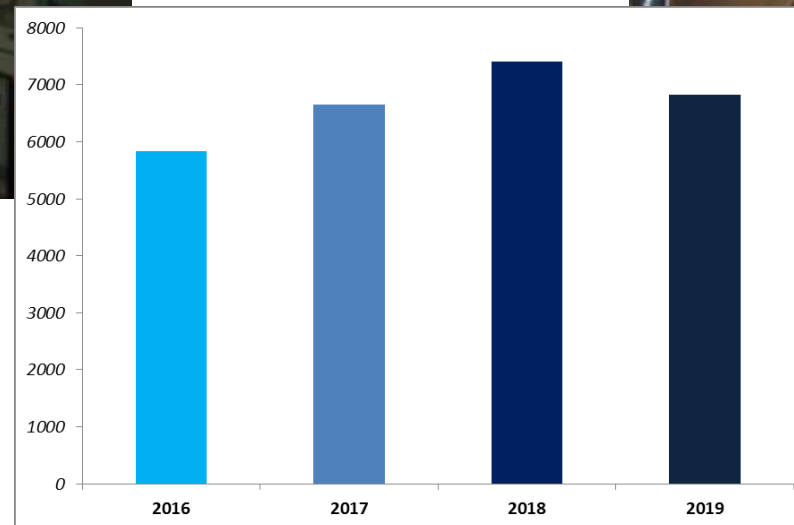
Tandem + Cyclotron beam time



35 - 40 experiments per year, including the proton therapy sessions

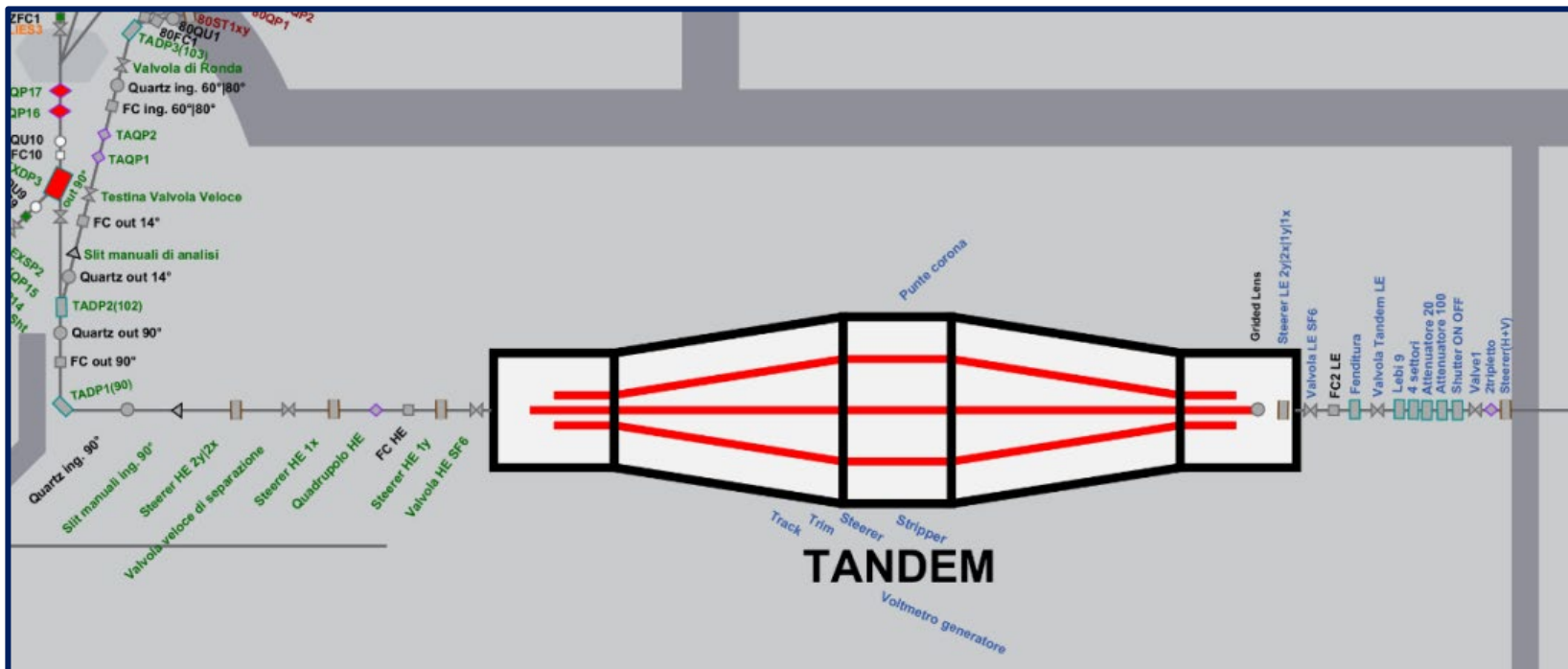
Beam time lost for failures:

- **Tandem: < 2%**
- **Cyclotron: < 4%**



430 BTU circa per year delivered for each accelerator
(excluding beam time preparation)

TANDEM automation and instrumentation upgrading



- Tandem vacuum system **February'23**
- Safety issues (RSPF prescriptions) **March'23**
- Switching magnet installation **May'23**
- Extra maintenance to electrical plant (compliance) **June'23**
- Extra maintenance to SF6 plant (controls with redundancy of temperature and pressure gauges, alarm leak) **July'23**
- Pelletron extra maintenance and relative tests (NEC discussion ongoing)
- HV stabilization system
- Alignment check
- Power converters
- Visual Diagnostics
- Spectrometry of accelerated species

Implementation of a new software platform

Replacement of obsolete instrumentation

First Tandem operation expected for end of 2023

Tandem Beam Menu

- ^1H , ^2H
- ^6Li , ^7Li
- ^9Be , ^{10}Be
- ^{10}B , ^{11}B
- ^{12}C , ^{13}C
- ^{14}N
- ^{16}O , ^{17}O , ^{18}O
- ^{19}F
- ^{23}Na
- ^{24}Mg , ^{25}Mg
- ^{27}Al
- ^{28}Si , ^{29}Si
- ^{32}S , ^{34}S
- ^{35}Cl , ^{37}Cl
- ^{40}Ca
- ^{58}Ni , ^{60}Ni
- ^{63}Cu , ^{65}Cu
- ^{70}Ge
- ^{79}Br
- ^{93}Nb
- ^{116}Sn , ^{120}Sn
- ^{127}I
- ^{197}Au

Maximum High Voltage $\approx 13.5\text{MV}$

Pelletron charging system

HV stability $\approx 10^{-4}$

Noble gases development in progress



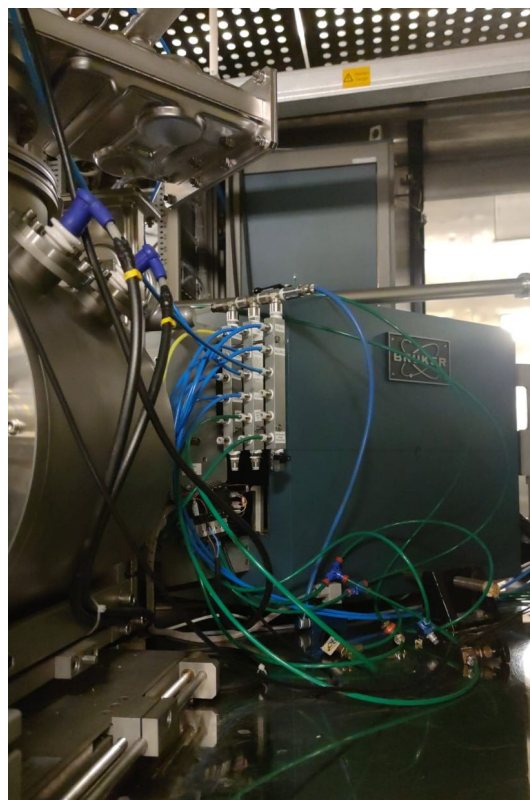
450kV PLATFORM



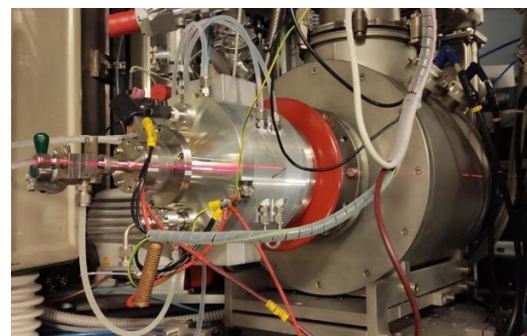
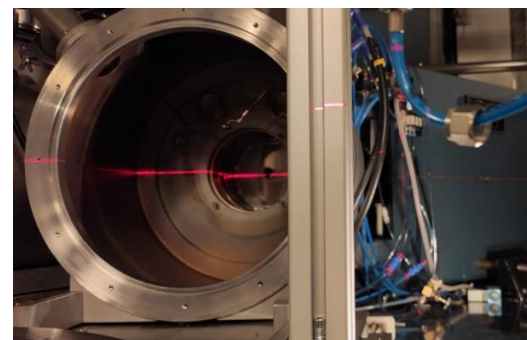
Extraordinary maintenance was carried out for all the subsystems



New Cooling Water
Distribution System



New Compressed Air
Distribution System



Alignment Check

TO DO:

- HV Distribution Rack:
adaptation to current
legislation



Planned for 2023

450kV PLATFORM



Extraordinary maintenance was carried out for all the subsystems



Vacuum cleaning

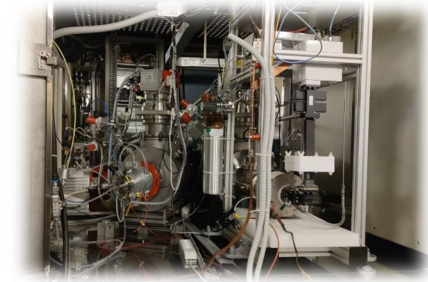


Vacuum Check



Istituto Nazionale di Fisica Nucleare
LABORATORI NAZIONALI DEL SUD

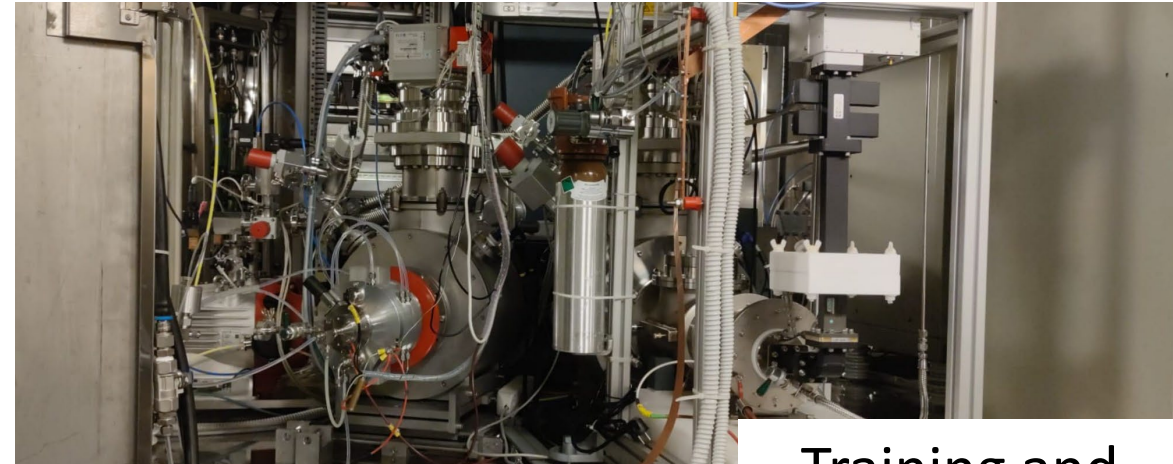
450kV PLATFORM-Sputter IS



First sputtering beam planned for January 2023

1. Gold -> reference beam
2. Aluminium
3. Lithium
4. Oxygen } from $\text{Li}_2\text{O}+\text{Ag}$
5. Magnesium from $\text{Mg} + \text{H}_2$ or $\text{Mg} + \text{NH}_3$
6. Carbon from $\text{BN} + \text{graphite}$ or B_4C

Approval of the HV Platform Safety Protocol by the RSPP



Training and Skills transfer



Protocollo di Sicurezza
Piattaforma 450kV

Document Control Sheet

Autore:	Cristina Lenardi
Revisore:	David Bello
Contributore:	Francesco DiBello
Versione:	01
Revisione:	Francesco DiBello
Approvato:	Cristina Lenardi
Approvato da:	Francesco DiBello

Document Revision History

Revisione	Autore	Revisione	Data
01	Inf Dept		11/02/22
02			

Sommario

1. SCOPO DEL DOCUMENTO..... 2
- 1.1. SCOPO DEL DOCUMENTO..... 2
- 1.2. DOCUMENTI DI RIFERIMENTO..... 2
- 1.3. ABBREVIAZIONI..... 2
2. DESCRIZIONE..... 3
3. MISURE DI SICUREZZA HV PIATTAFORMA..... 3

1

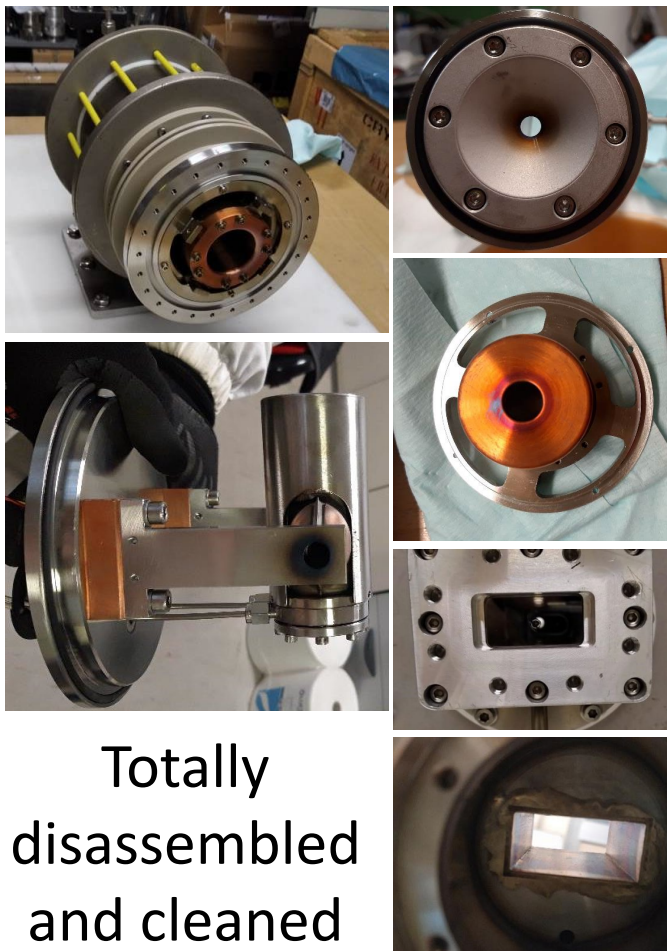
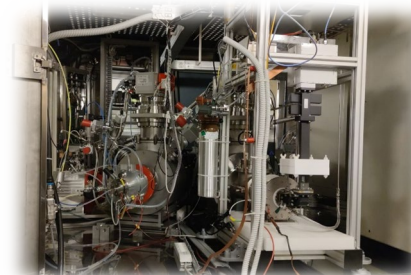
L. Celona, INFN-LNS Users Annual Meeting

SHOT ON MI 10T PRO

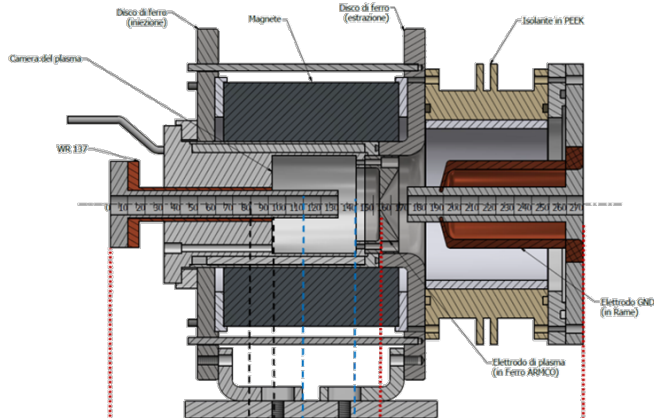


Istituto Nazionale di Fisica Nucleare
LABORATORI NAZIONALI DEL SUD

450kV PLATFORM-NESTOR



Totally disassembled and cleaned



New characterization is planned for January

Protocollo Operativo Nestor
Attività Sperimentali 2023

Document Control Sheet

Titolo	Autore	G. Lavarello
DATA	Contributore	G. Carini
Versioni	Revisore/Controllore	G. Lavarello
	Approvatore	

Document Revision History

Rev.	Descrizione	Data
01	Primo Draft	06/05/2023
02	Final Draft	07/07/2023

1. INTRODUZIONE

1.1. Scopo del documento

1.2. Documenti di riferimento

Ref. Number	Titolo

1.3. Approvato

Autore	Approvatore

1.4. Caratterizzazione base di He

1.5. Impresione di CEC attiva

1.6. Impresione di CEC passiva

1.7. Impresione di CEC attiva

1.8. Impresione di CEC passiva

1.9. Impresione di CEC attiva

1.10. Impresione di CEC passiva

1.11. Impresione di CEC attiva

1.12. Impresione di CEC passiva

1.13. Impresione di CEC attiva

1.14. Impresione di CEC passiva

1.15. Impresione di CEC attiva

1.16. Impresione di CEC passiva

1.17. Impresione di CEC attiva

1.18. Impresione di CEC passiva

1.19. Impresione di CEC attiva

1.20. Impresione di CEC passiva

1.21. Impresione di CEC attiva

1.22. Impresione di CEC passiva

1.23. Impresione di CEC attiva

1.24. Impresione di CEC passiva

1.25. Impresione di CEC attiva

1.26. Impresione di CEC passiva

1.27. Impresione di CEC attiva

1.28. Impresione di CEC passiva

1.29. Impresione di CEC attiva

1.30. Impresione di CEC passiva

1.31. Impresione di CEC attiva

1.32. Impresione di CEC passiva

1.33. Impresione di CEC attiva

1.34. Impresione di CEC passiva

1.35. Impresione di CEC attiva

1.36. Impresione di CEC passiva

1.37. Impresione di CEC attiva

1.38. Impresione di CEC passiva

1.39. Impresione di CEC attiva

1.40. Impresione di CEC passiva

1.41. Impresione di CEC attiva

1.42. Impresione di CEC passiva

1.43. Impresione di CEC attiva

1.44. Impresione di CEC passiva

1.45. Impresione di CEC attiva

1.46. Impresione di CEC passiva

1.47. Impresione di CEC attiva

1.48. Impresione di CEC passiva

1.49. Impresione di CEC attiva

1.50. Impresione di CEC passiva

1.51. Impresione di CEC attiva

1.52. Impresione di CEC passiva

1.53. Impresione di CEC attiva

1.54. Impresione di CEC passiva

1.55. Impresione di CEC attiva

1.56. Impresione di CEC passiva

1.57. Impresione di CEC attiva

1.58. Impresione di CEC passiva

1.59. Impresione di CEC attiva

1.60. Impresione di CEC passiva

1.61. Impresione di CEC attiva

1.62. Impresione di CEC passiva

1.63. Impresione di CEC attiva

1.64. Impresione di CEC passiva

1.65. Impresione di CEC attiva

1.66. Impresione di CEC passiva

1.67. Impresione di CEC attiva

1.68. Impresione di CEC passiva

1.69. Impresione di CEC attiva

1.70. Impresione di CEC passiva

1.71. Impresione di CEC attiva

1.72. Impresione di CEC passiva

1.73. Impresione di CEC attiva

1.74. Impresione di CEC passiva

1.75. Impresione di CEC attiva

1.76. Impresione di CEC passiva

1.77. Impresione di CEC attiva

1.78. Impresione di CEC passiva

1.79. Impresione di CEC attiva

1.80. Impresione di CEC passiva

1.81. Impresione di CEC attiva

1.82. Impresione di CEC passiva

1.83. Impresione di CEC attiva

1.84. Impresione di CEC passiva

1.85. Impresione di CEC attiva

1.86. Impresione di CEC passiva

1.87. Impresione di CEC attiva

1.88. Impresione di CEC passiva

1.89. Impresione di CEC attiva

1.90. Impresione di CEC passiva

1.91. Impresione di CEC attiva

1.92. Impresione di CEC passiva

1.93. Impresione di CEC attiva

1.94. Impresione di CEC passiva

1.95. Impresione di CEC attiva

1.96. Impresione di CEC passiva

1.97. Impresione di CEC attiva

1.98. Impresione di CEC passiva

1.99. Impresione di CEC attiva

2.00. Impresione di CEC passiva

2.01. Impresione di CEC attiva

2.02. Impresione di CEC passiva

2.03. Impresione di CEC attiva

2.04. Impresione di CEC passiva

2.05. Impresione di CEC attiva

2.06. Impresione di CEC passiva

2.07. Impresione di CEC attiva

2.08. Impresione di CEC passiva

2.09. Impresione di CEC attiva

2.10. Impresione di CEC passiva

2.11. Impresione di CEC attiva

2.12. Impresione di CEC passiva

2.13. Impresione di CEC attiva

2.14. Impresione di CEC passiva

2.15. Impresione di CEC attiva

2.16. Impresione di CEC passiva

2.17. Impresione di CEC attiva

2.18. Impresione di CEC passiva

2.19. Impresione di CEC attiva

2.20. Impresione di CEC passiva

2.21. Impresione di CEC attiva

2.22. Impresione di CEC passiva

2.23. Impresione di CEC attiva

2.24. Impresione di CEC passiva

2.25. Impresione di CEC attiva

2.26. Impresione di CEC passiva

2.27. Impresione di CEC attiva

2.28. Impresione di CEC passiva

2.29. Impresione di CEC attiva

2.30. Impresione di CEC passiva

2.31. Impresione di CEC attiva

2.32. Impresione di CEC passiva

2.33. Impresione di CEC attiva

2.34. Impresione di CEC passiva

2.35. Impresione di CEC attiva

2.36. Impresione di CEC passiva

2.37. Impresione di CEC attiva

2.38. Impresione di CEC passiva

2.39. Impresione di CEC attiva

2.40. Impresione di CEC passiva

2.41. Impresione di CEC attiva

2.42. Impresione di CEC passiva

2.43. Impresione di CEC attiva

2.44. Impresione di CEC passiva

2.45. Impresione di CEC attiva

2.46. Impresione di CEC passiva

2.47. Impresione di CEC attiva

2.48. Impresione di CEC passiva

2.49. Impresione di CEC attiva

2.50. Impresione di CEC passiva

2.51. Impresione di CEC attiva

2.52. Impresione di CEC passiva

2.53. Impresione di CEC attiva

2.54. Impresione di CEC passiva

2.55. Impresione di CEC attiva

2.56. Impresione di CEC passiva

2.57. Impresione di CEC attiva

2.58. Impresione di CEC passiva

2.59. Impresione di CEC attiva

2.60. Impresione di CEC passiva

2.61. Impresione di CEC attiva

2.62. Impresione di CEC passiva

2.63. Impresione di CEC attiva

2.64. Impresione di CEC passiva

2.65. Impresione di CEC attiva

2.66. Impresione di CEC passiva

2.67. Impresione di CEC attiva

2.68. Impresione di CEC passiva

2.69. Impresione di CEC attiva

2.70. Impresione di CEC passiva

2.71. Impresione di CEC attiva

2.72. Impresione di CEC passiva

2.73. Impresione di CEC attiva

2.74. Impresione di CEC passiva

2.75. Impresione di CEC attiva

2.76. Impresione di CEC passiva

2.77. Impresione di CEC attiva

2.78. Impresione di CEC passiva

2.79. Impresione di CEC attiva

2.80. Impresione di CEC passiva

2.81. Impresione di CEC attiva

2.82. Impresione di CEC passiva

2.83. Impresione di CEC attiva

2.84. Impresione di CEC passiva

2.85. Impresione di CEC attiva

2.86. Impresione di CEC passiva

2.87. Impresione di CEC attiva

2.88. Impresione di CEC passiva

2.89. Impresione di CEC attiva

2.90. Impresione di CEC passiva

2.91. Impresione di CEC attiva

2.92. Impresione di CEC passiva

2.93. Impresione di CEC attiva

2.94. Impresione di CEC passiva

2.95. Impresione di CEC attiva

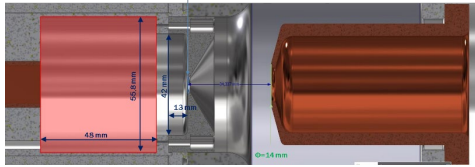
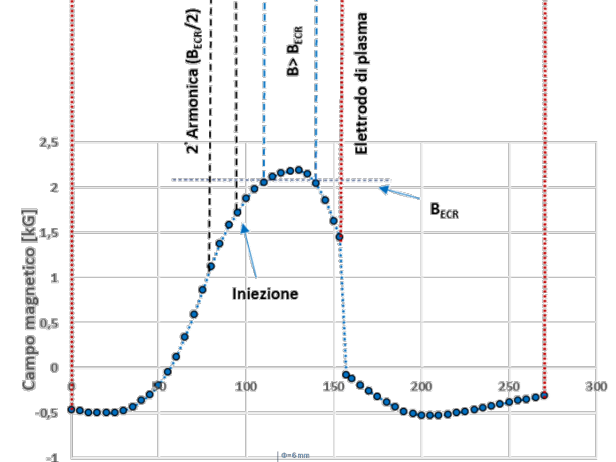
2.96. Impresione di CEC passiva

2.97. Impresione di CEC attiva

2.98. Impresione di CEC passiva

2.99. Impresione di CEC attiva

3.00. Impresione di CEC passiva



Planned operations:

- Positive He production and relative transport along the beam line in different conditions and operations
- Charge-exchange cell installation and test of production of negative ion beams in different conditions and operations.
- Open issues resolution

Long half-life isotopes in batch-mode

^{10}Be ($T_{1/2} = 1.39 \times 10^6 \text{ y}$) Tandem beam has been produced in batch-mode, in collaboration with PSI (Zurich)

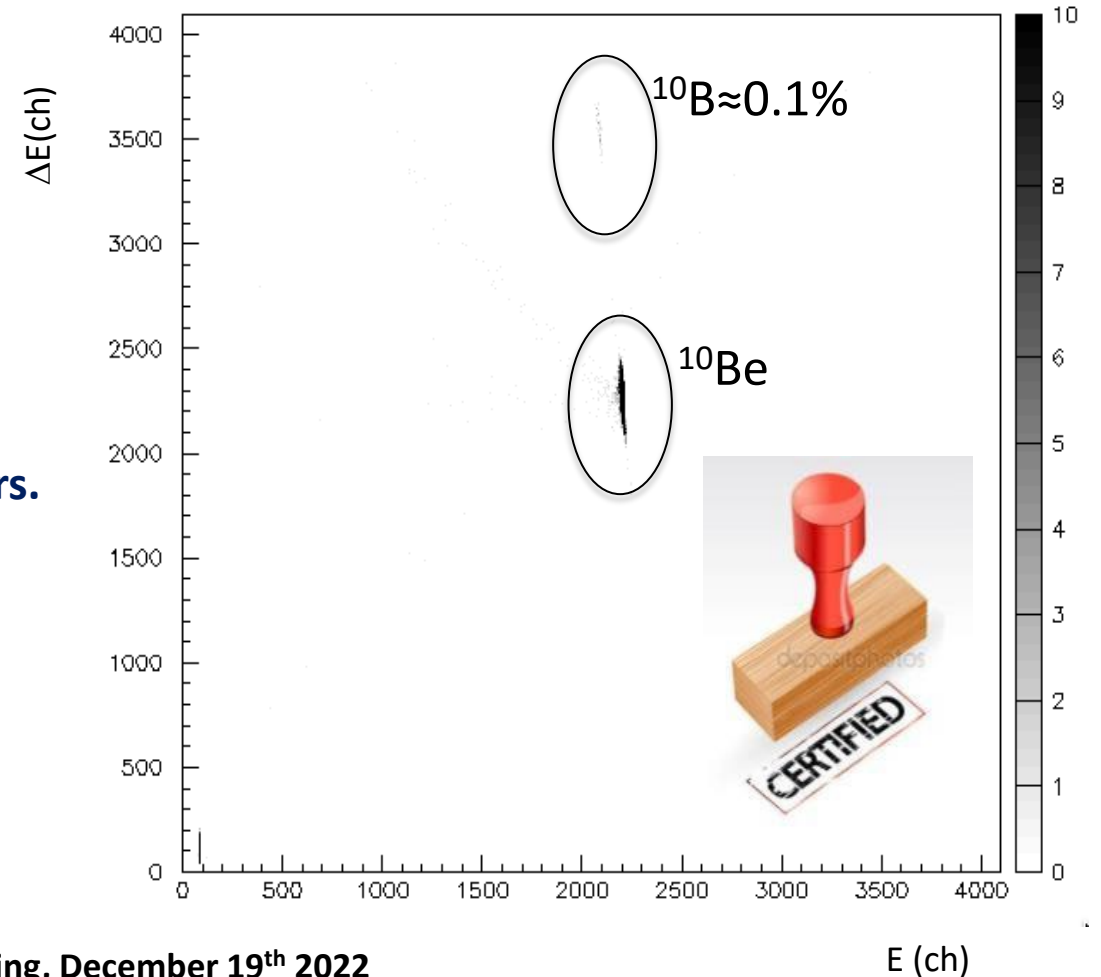
@ 47 MeV

$I \approx 10 \text{ nA}$ for a few days

Contamination of $^{10}\text{B} \approx 0.1\%$

Batch-mode beam development is foreseen for the next years.

Next possible beam: **^{26}Al** ($T_{1/2} = 7.17 \times 10^5 \text{ y}$)



Superconducting Cyclotron

Operating 1994 - 2020

$E_{\text{MAX}} \sim 80 \text{ AMeV}$ for lighter ions

$E_{\text{MAX}} \sim 25 \text{ AMeV}$ for heavier ions (i.e. Au^{36+})

$K_{\text{bend}} = 800 - K_{\text{foc}} = 200$

Pole radius: 90 cm – Mag. field: 2.2 - 4.8 T

RF range: 15-48 MHz

Since 1999

Two ECR ion sources: CAESAR and SERSE

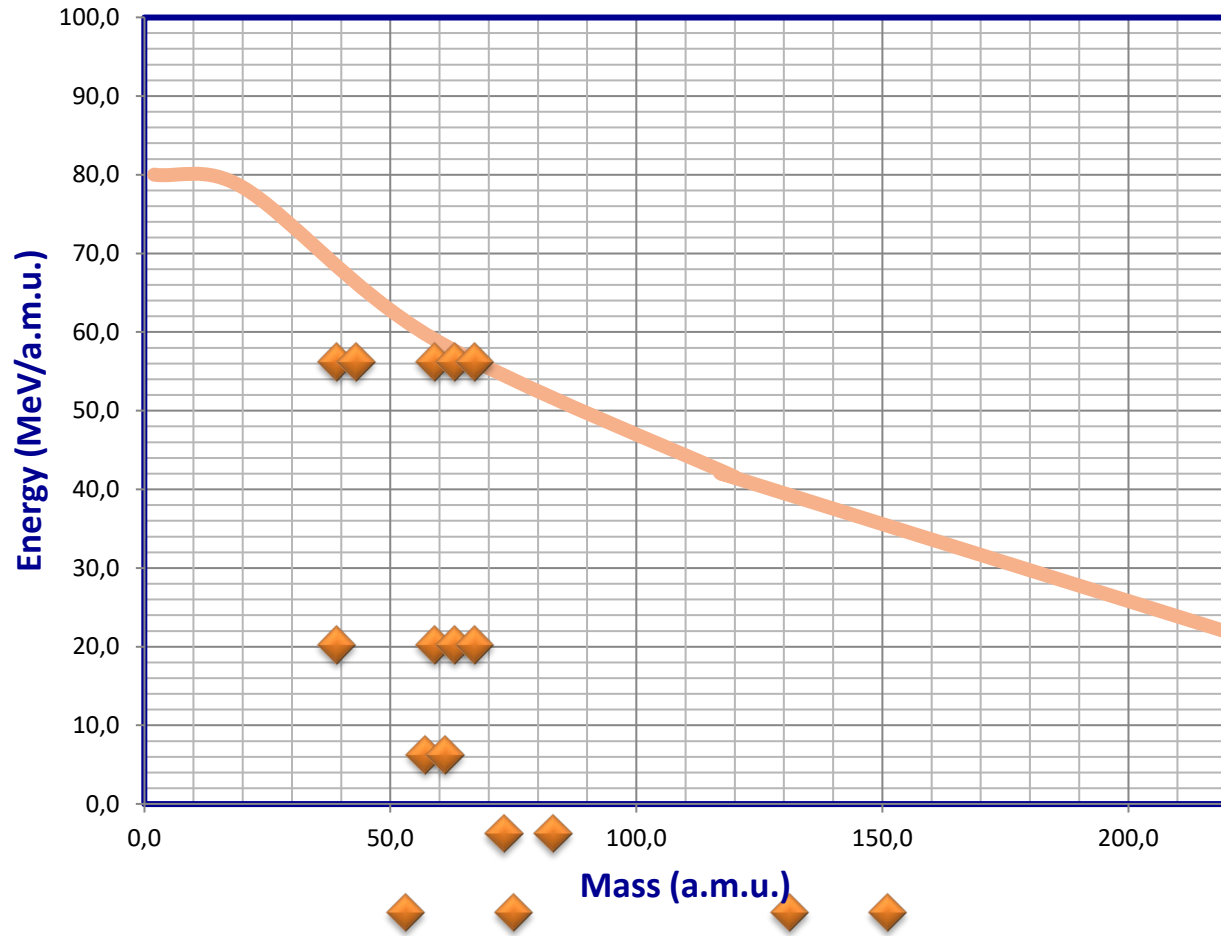
June 2020 last experiment, disassembly for the upgrading started in November.





Istituto Nazionale di Fisica Nucleare
LABORATORI NAZIONALI DEL SUD

Cyclotron Beams Menu

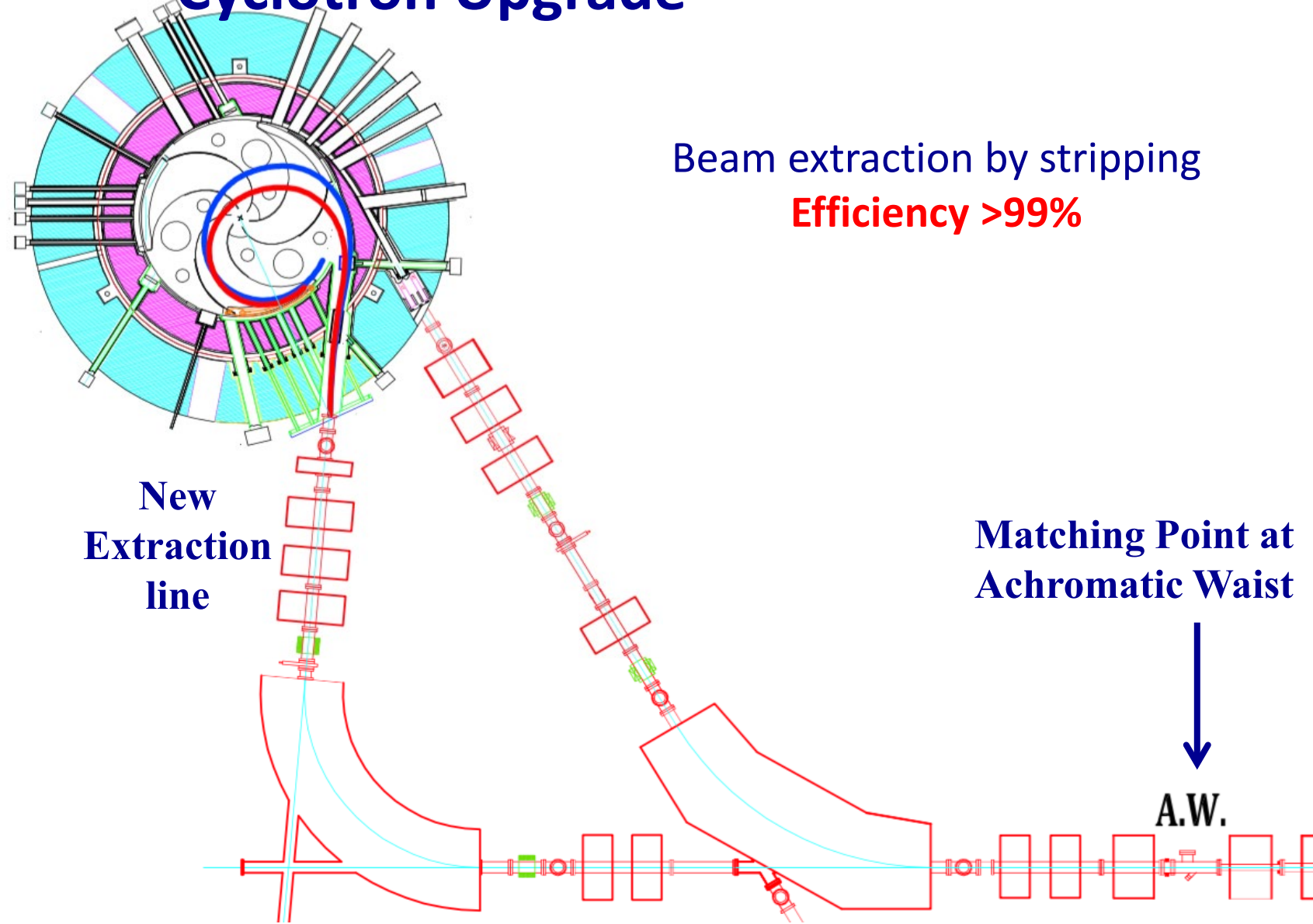


A X	E (AMeV)
H_2^+	62,80
H_3^+	30,35,45
$^2D^+$	35,62,80
4He	25,62,80
He-H	10, 21
9Be	45
^{11}B	55
^{12}C	23,62,80
^{13}C	45,55
^{14}N	62,80
^{16}O	21,25,55,62,80
^{18}O	15,55
^{19}F	35,40,50
^{20}Ne	20,40,45,62
^{24}Mg	50
^{27}Al	40
^{36}Ar	16,38
^{40}Ar	15,20,40

A X	E (AMeV)
^{40}Ca	10,25,40,45
$^{42,48}Ca$	10,45
^{58}Ni	16,23,25,30,35,40,45
$^{62,64}Ni$	25,35
$^{68,70}Zn$	40
^{74}Ge	40
$^{78,86}Kr$	10
^{84}Kr	10,15,20,25
^{93}Nb	15,17,23,30,38
^{107}Ag	40
^{112}Sn	15.5,35,43.5
^{116}Sn	23,30,38
^{124}Sn	15,25,30,35
^{129}Xe	20,21,23,35
^{197}Au	10,15,20,21,23
^{208}Pb	10

Cyclotron Upgrade

Instantaneous change of the **magnetic rigidity**, when the **charge state of the ion** is suddenly increased crossing a thin carbon foil.



Cyclotron Upgrade: expected currents by stripping

Ion	q	Energy MeV/u	I _{source} eμA	I _{acc} eμA	I _{extract} eμA	rate pps
12C	4	18	400	60	90.0	9.5E+13
12C	4	30	200	30	45.0	4.7E+13
12C	4	45	400	60	90.0	9.5E+13
12C	4	60	400	60	90.0	9.5E+13
18O	6	20	400	60	80.0	6.3E+13
18O	6	29	400	60	80.0	6.3E+13
18O	6	45	400	60	80.0	6.3E+13
18O	6	60	400	60	80.0	6.3E+13
18O	7	70	200	30	34.3	2.7E+13
20Ne	4	15	600	90	225.0	1.4E+14
20Ne	7	28	400	60	85.7	5.4E+13
20Ne	7	60	400	60	85.7	5.4E+13
40Ar	13	60	300	45	20.8	1.0E+13

18O @ 20 MeV will be the beam used to commissioning of the machine:

- It is in a good area of operative diagram of the machine.
- The power is not too high and it could mitigate eventually activation issues during the commissioning phase.

During the commissioning of the machine the beam intensity will be increased step by step adjusting the duty cycle of the CHOPPER, monitoring the beam losses along the beam lines and optimizing the tuning to minimize them.

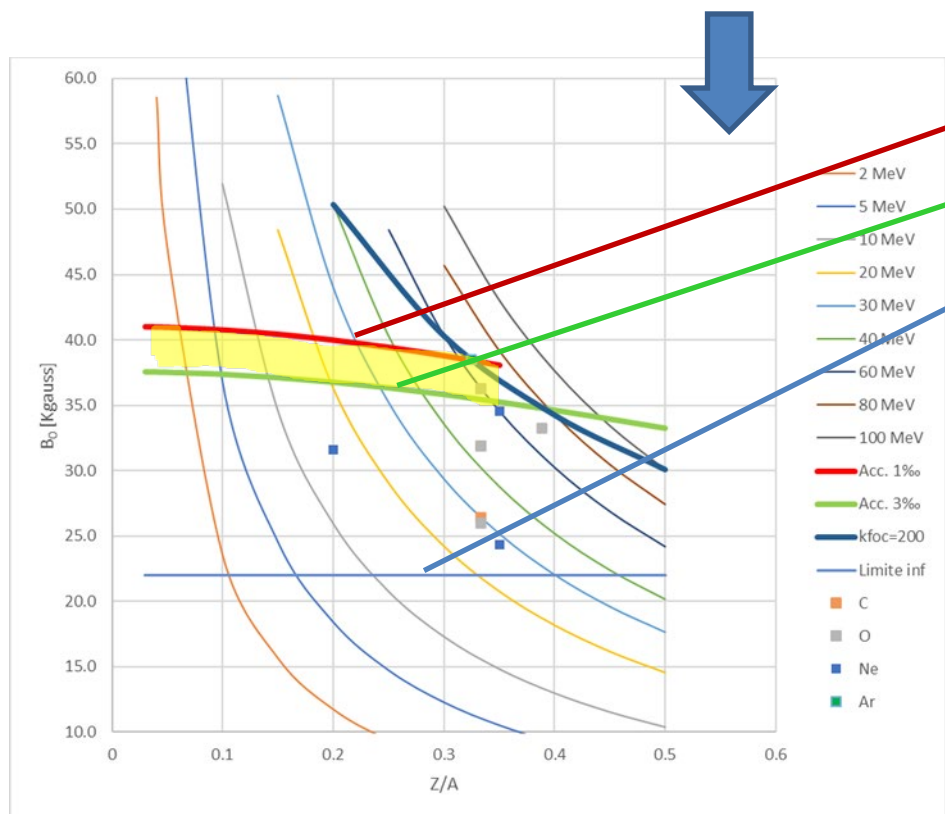
To increase the current accelerated the following parameters need to be checked during the operation:

- 1) **Beam currents at the beam dump** increased of the expected value set by chopper;
- 2) **Beam losses at control slits** installed on the stripping **exit channel** of cyclotron stay below the threshold of 200 W;
- 3) **Beam losses along the five beam transport rooms** monitored by Radioprotection service stay below the threshold corresponding to 100 W beam loss;
- 4) All the 8 **beam current monitors** (CWCT) along the beam lines measure the expected values;
- 5) All the **slits that intercept the beam halo** along the beam lines measure the expected values.

Coil performances vs Operative diagram

Deviation from the ideal form factor is expected.

Trim coils may help to contain this deviation, **minimizing** the performance reduction in terms of operative diagram.



Upper limit of the magnetic field that should be correct within 0.1%

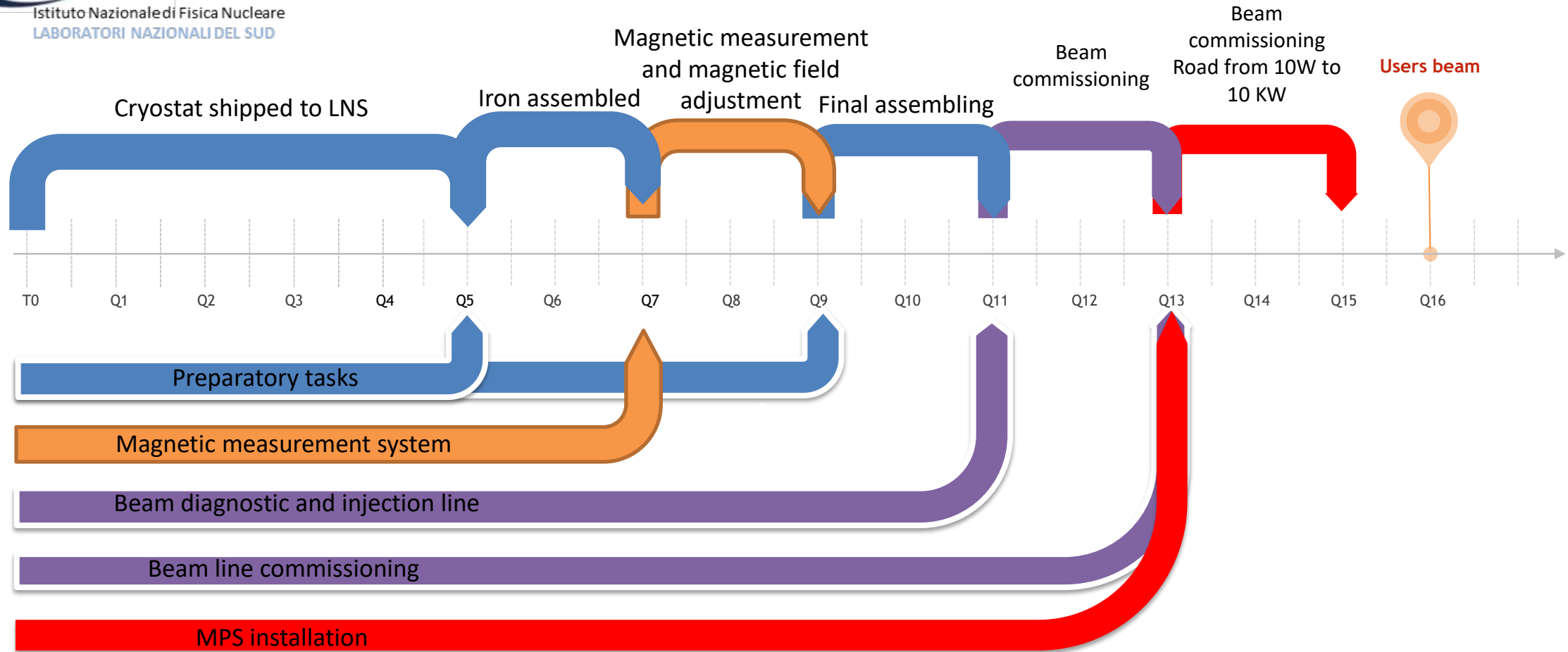
Case when the accuracy is 0,3%.

Lower limit

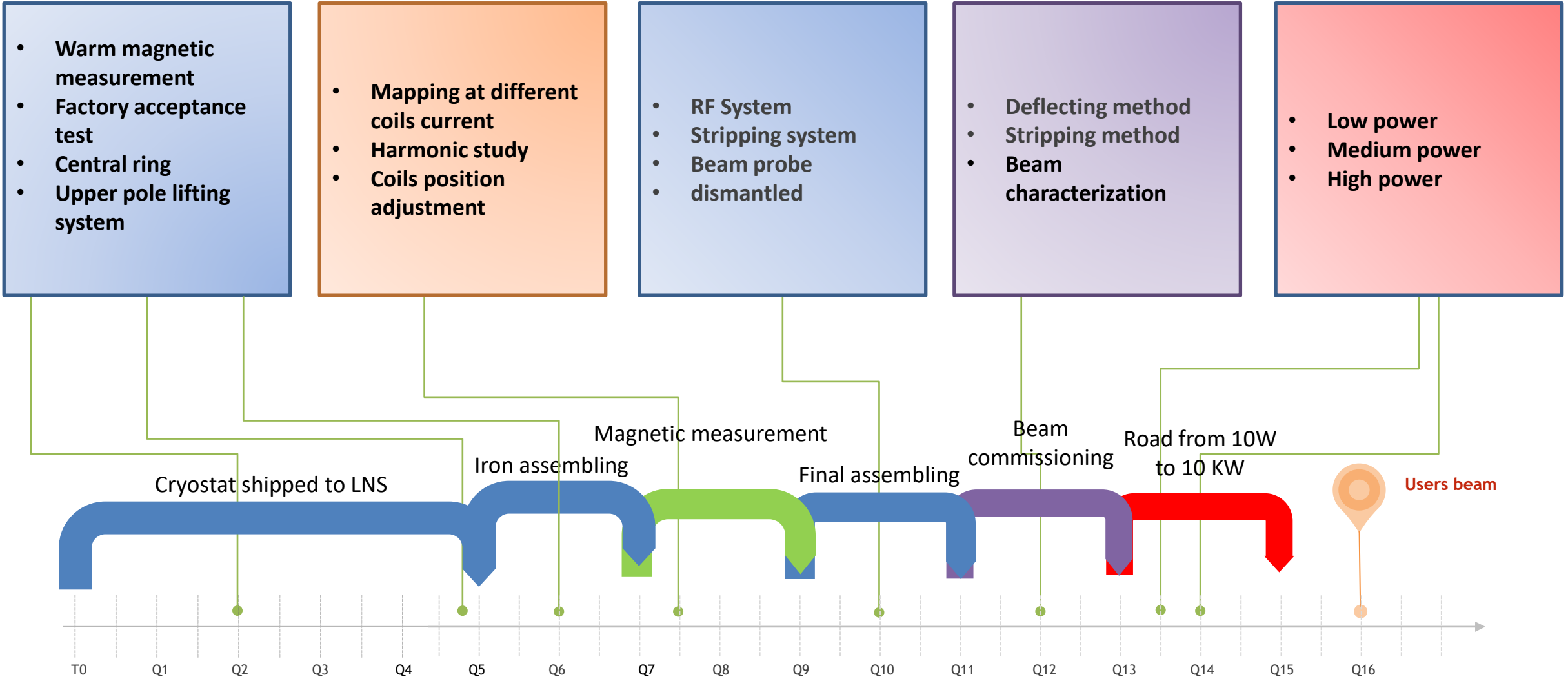


Beam dynamics simulation in progress.
Warm coil qualification will permit to refine the studies.

Masterplan



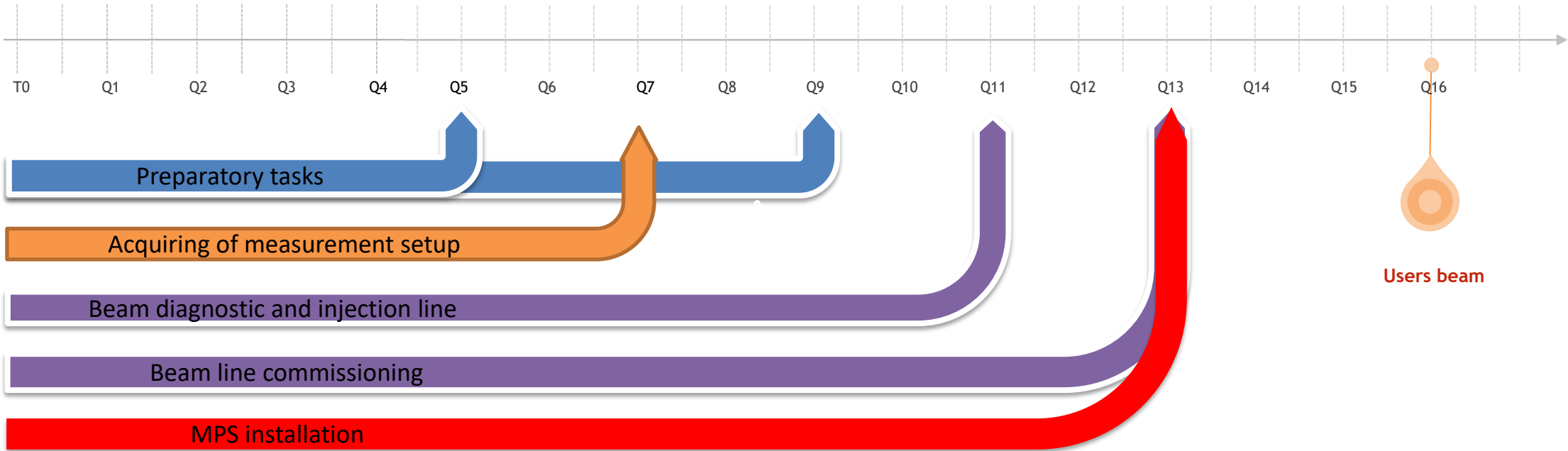
Masterplan





Istituto Nazionale di Fisica Nucleare
LABORATORI NAZIONALI DEL SUD

Masterplan



- Iron Cleaning
- Cavity Maintenance
- Liner installation
- Trim coils Maintenance
- Services restyling

- Probe positioning system
- Measurement probe

- Beam current probes on the machine
- Magnetic channel
- Injection line
- Chopper system

- New beam lines
- Diagnostic system
- New services
- Control system

- Control integration
- Cabling
- Testing

ECR ion sources



SERSE (1997)

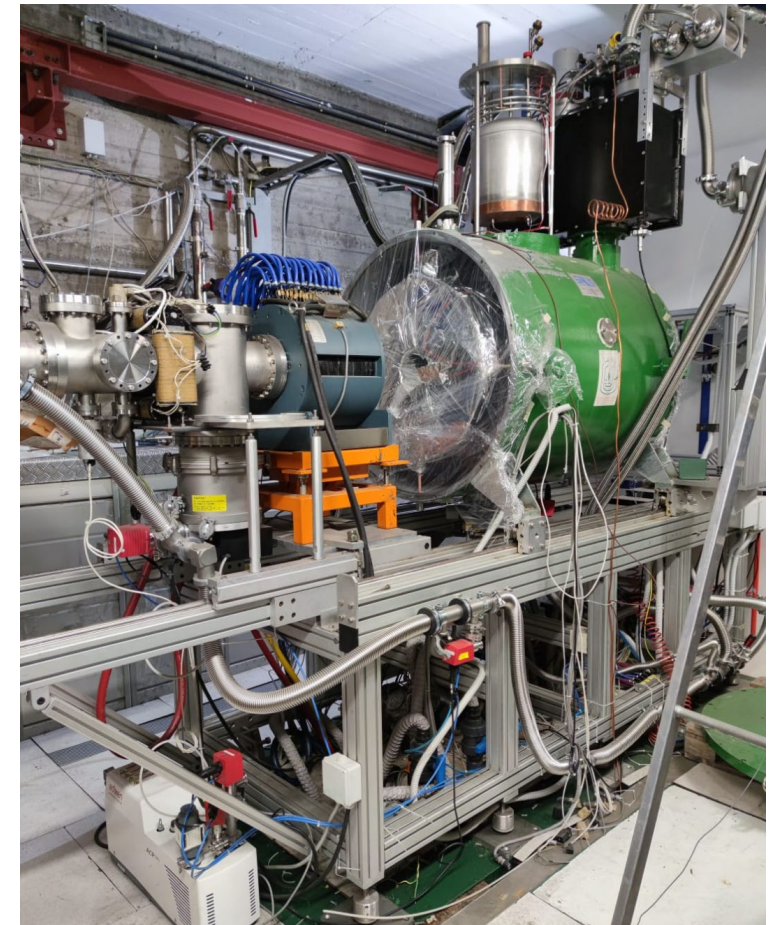


Refurbishment of some subsystems carried out in previous years (controls, gas box, insulated rack), **but serious cryogenic problem** arose during last operations.

Activities carried out in summer 2022 to understand the possibility to revamp the cryogenic system, thanks to the addition of a third Single-Stage Pulse Tube to increase the refrigeration power of the nitrogen screen.

Unfortunately, the mechanics of the cryostat does not allow the creation of efficient thermal links.

**HIGH INTENSITY operation and HCl production
REQUIRE SERSE or a similar class ECR Ion Source**



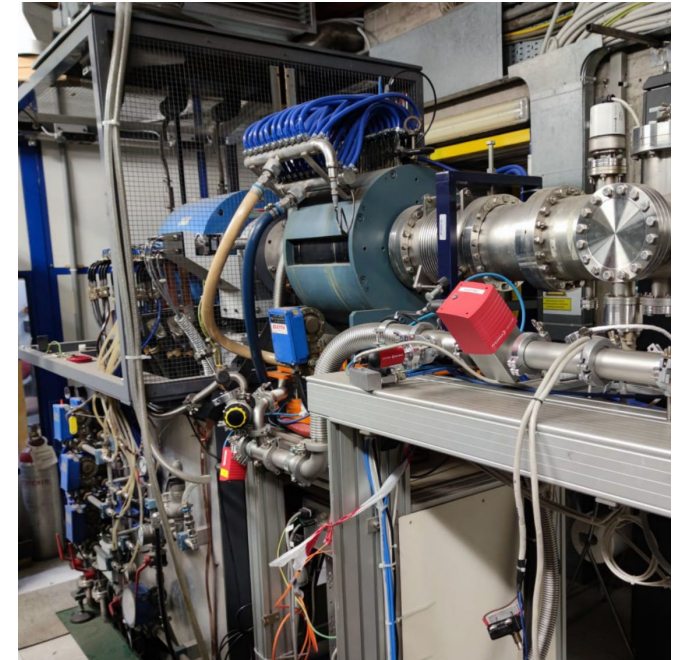
CAESAR (1999)



The CAESAR ion source, although totally unsuitable to support the high intensities desired with the new CS, could continue to provide the less critical beams in the first operational years after a revamping of some subsystems (Obsolete Vacuum automation system, Vacuum and alignments check on the LEBT).

Other criticalities

- ECR room shall be splitted to permit maintenance on one source while operating with the other.

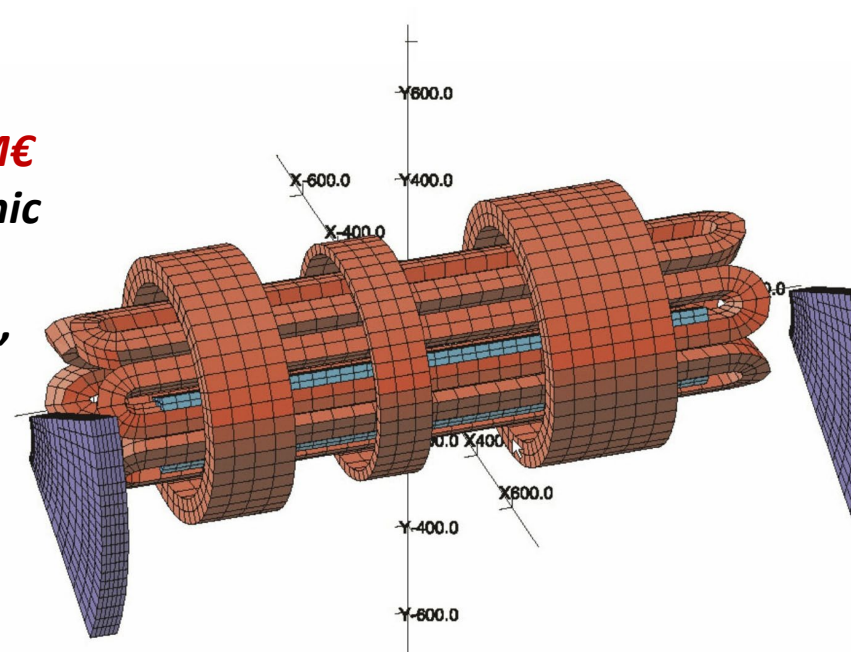


SC-AISHa: a new ion source for INFN-LNS

- The AISHa ion source has been expressly conceived and realized for actual and future hadrontherapy facility (e.g.: HITRI+). It has a strong limitation on a radial field (1.28T instead of 1.55T of SERSE) affecting HCl production.
- A fully superconducting version has been conceived to overcome such limitation.

Radial field	1.9 T
Axial field	3.5 T - 0.5 T - 2.2 T
Operating frequencies	24 GHz - 18 GHz
Operating power	5 + 5 kW (max)
Extraction voltage	50 kV (max)
Chamber diameter / length	Ø 130 mm / 500 mm
LHe	Free
Warm bore diameter	140 mm
Source weight	2100 kg

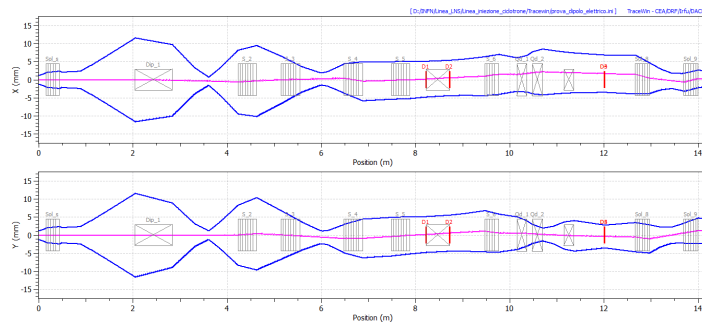
Cost expected: 1.62 M€
(body source, cryogenic
equipment for
standalone operation,
mechanics)



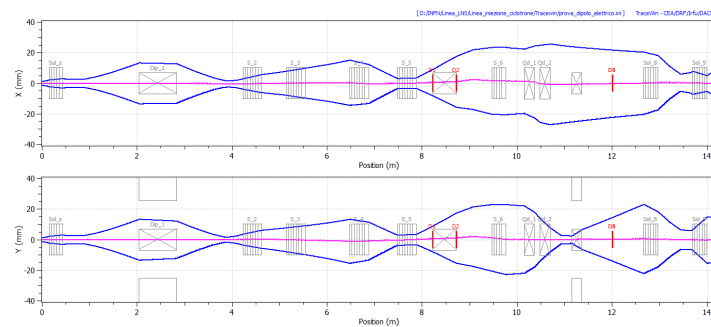
Axial injection beam line

12C⁴⁺ @ 10 AkeV

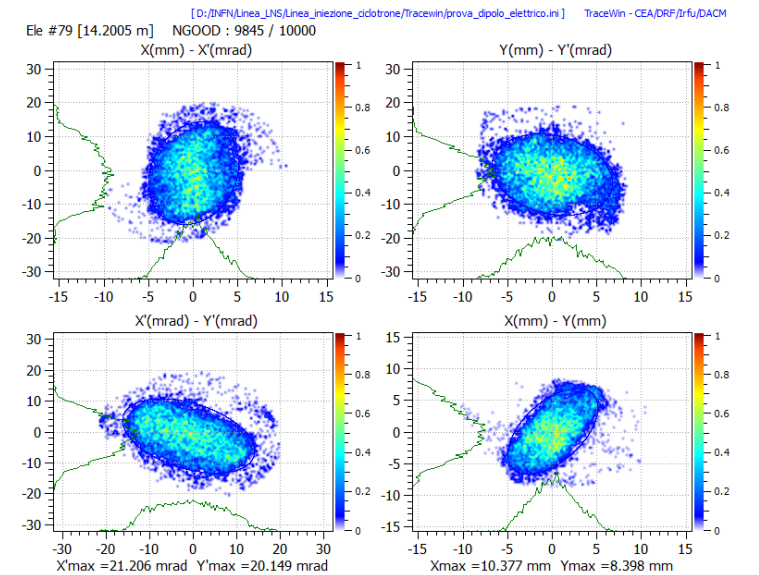
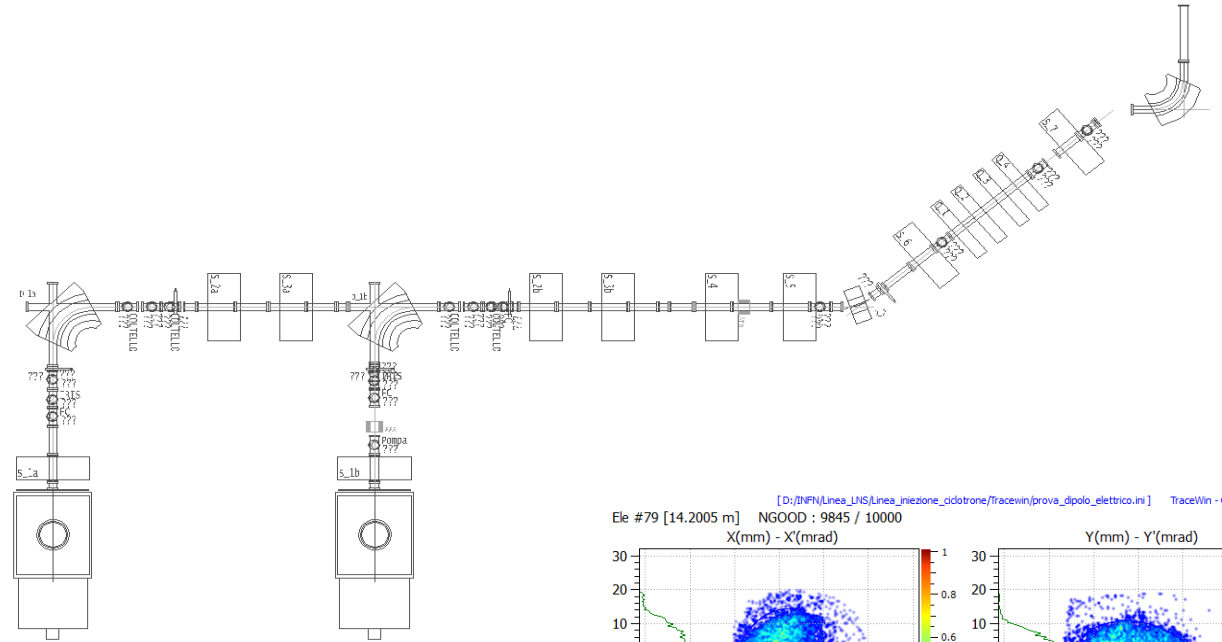
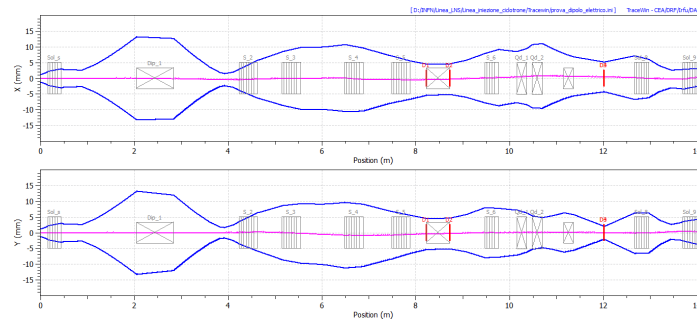
I=0 mA



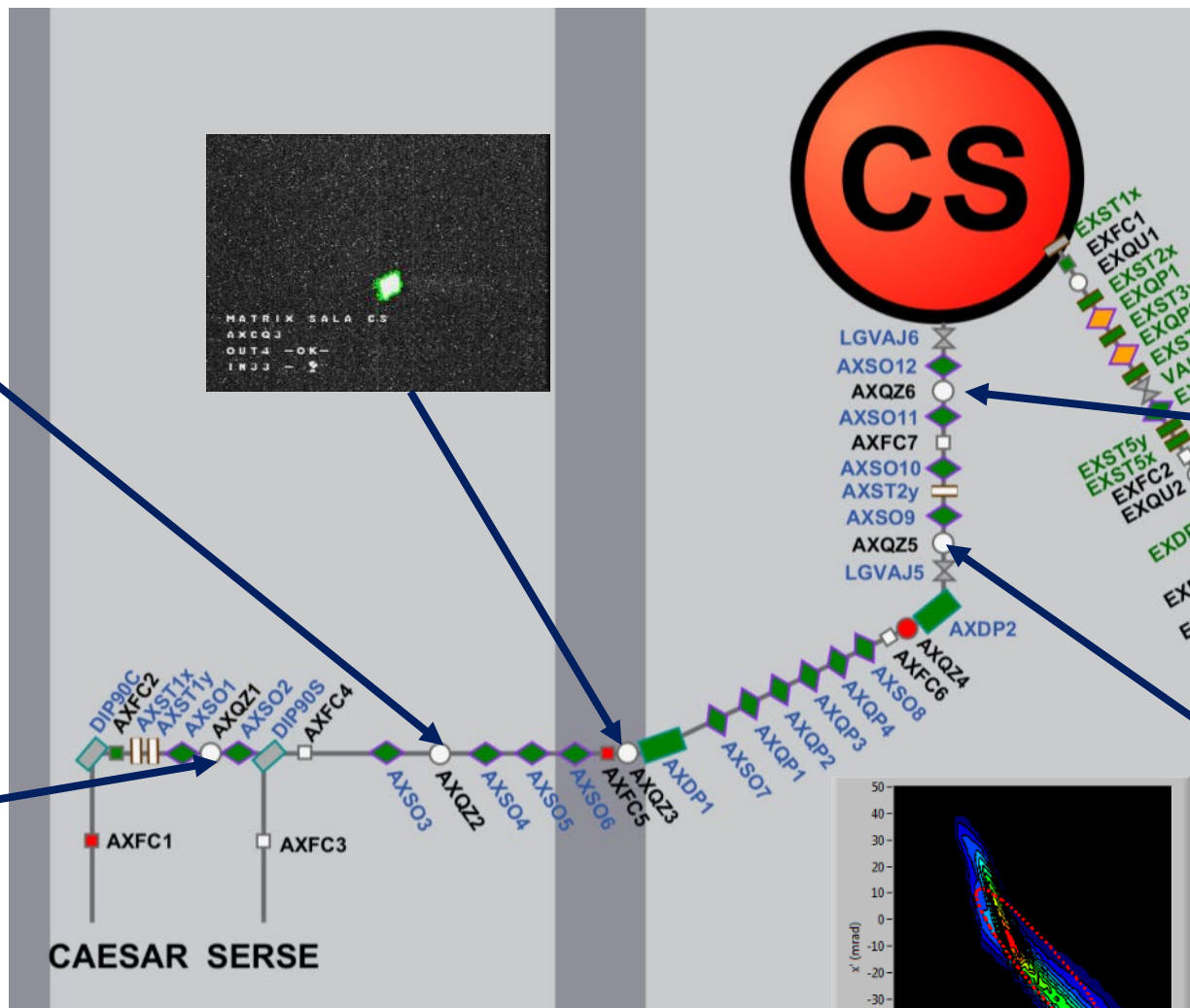
I=0.5emA-Not optimized



optimized



Ion Sources – Cyclotron matching optimization



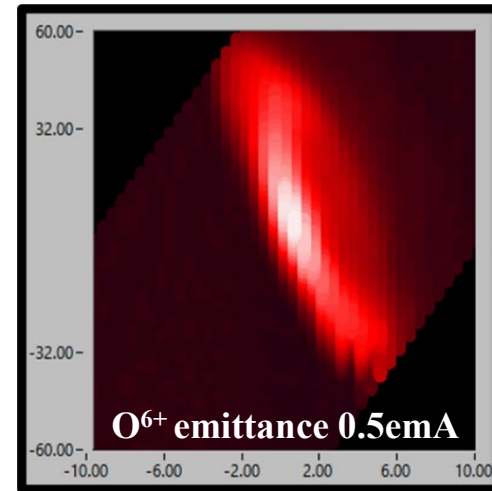
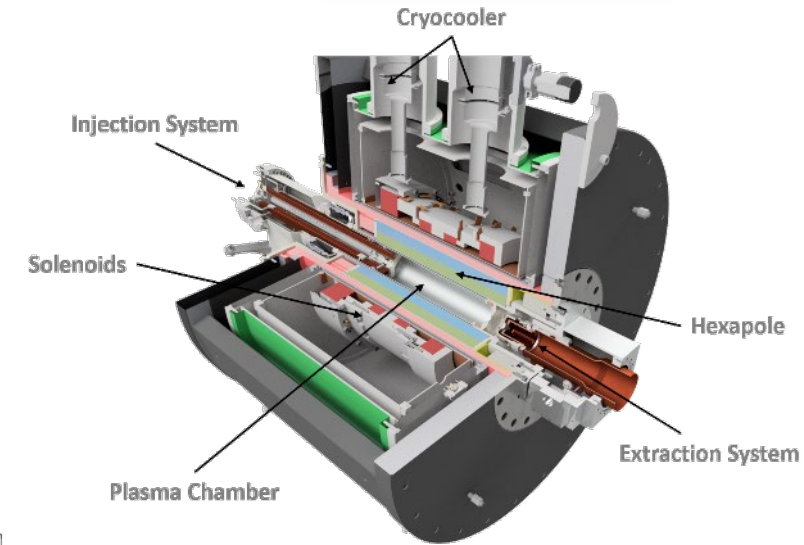


Istituto Nazionale di Fisica Nucleare
LABORATORI NAZIONALI DEL SUD

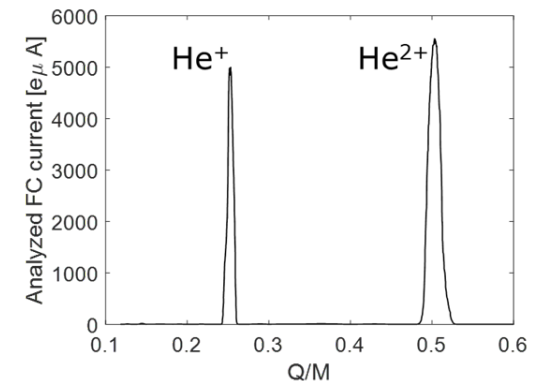
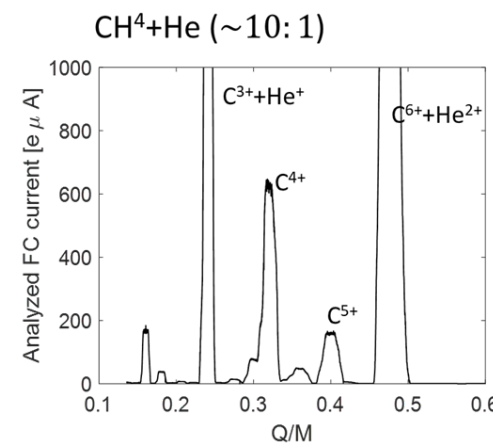
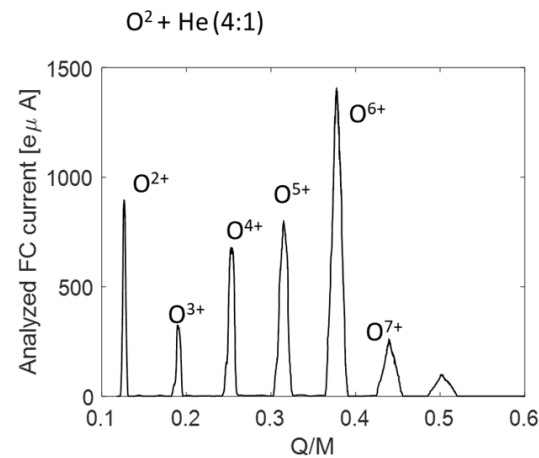
AISHa: a testbench for INFN-LNS

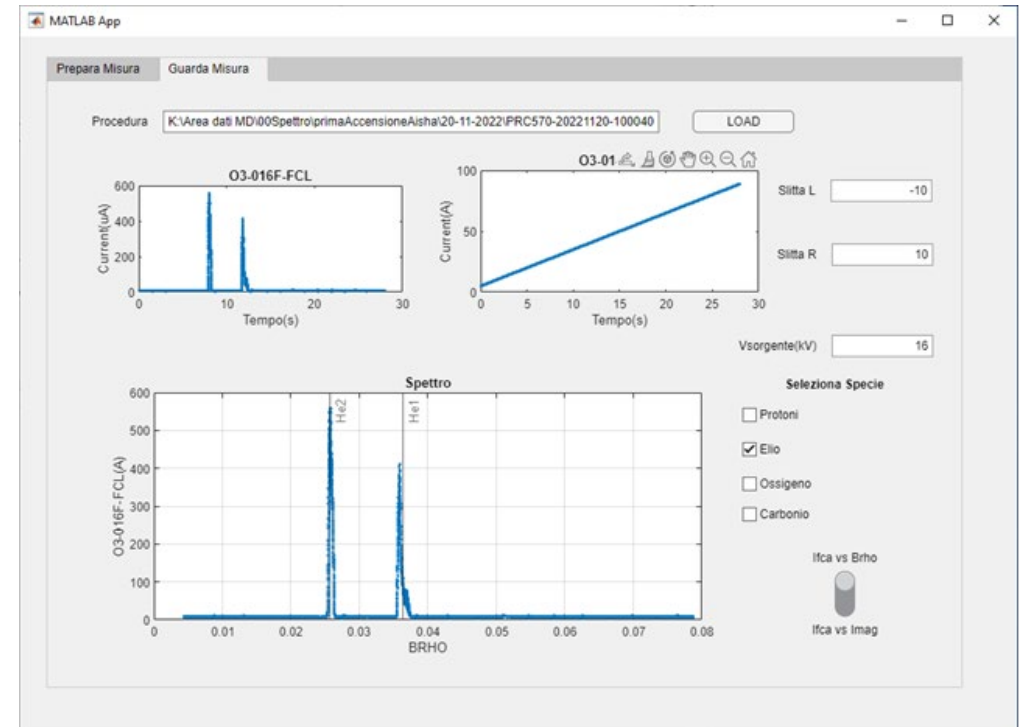
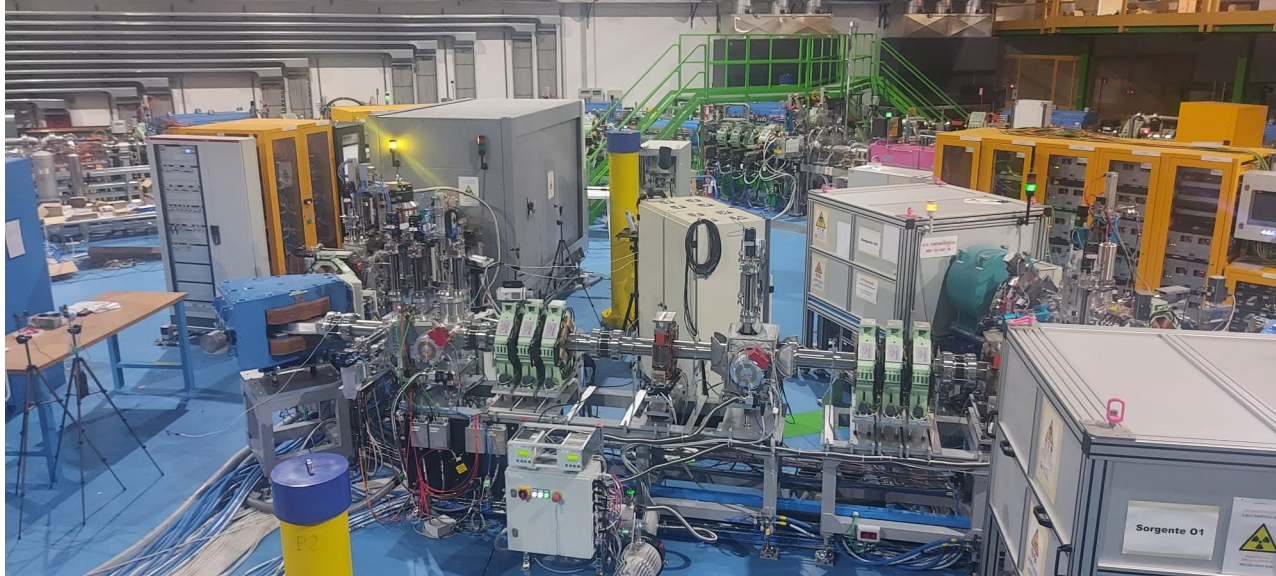
AISHa source has been moved to a new room to permit the civil works of CS upgrading.

Installation of craine and services needed to operate is expected for June'23 and restart of operation is planned for October'23



Charge state	Beam intensity [eμA]	$\epsilon_{rms, norm}$ [$\pi \cdot mm \cdot mrad$]
$^{16}O^{6+}$	1400	0.2198
$^{16}O^{6+}$	225	0.115
$^{16}O^{7+}$	350	0.247
$^{12}C^{4+}$	650	0.272
$^{12}C^{4+}$	150	0.222
$^{12}C^{5+}$	165	---
$^{40}Ar^{11+}$	155	0.201
$^{40}Ar^{12+}$	140	0.201
He^{2+}	5400	0.418
He^{2+}	700	0.245





Ion	AISHa Performances [uA]	Requirement CNAO [uA]
C ⁴⁺	520	110
O ⁶⁺	1200	64
He ²⁺	5400	344
Li ³⁺	To be developed	230
Fe ¹⁹⁺	To be developed	175

**First beam produced on
19/11/22 (He@16kV).**

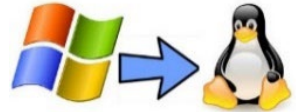
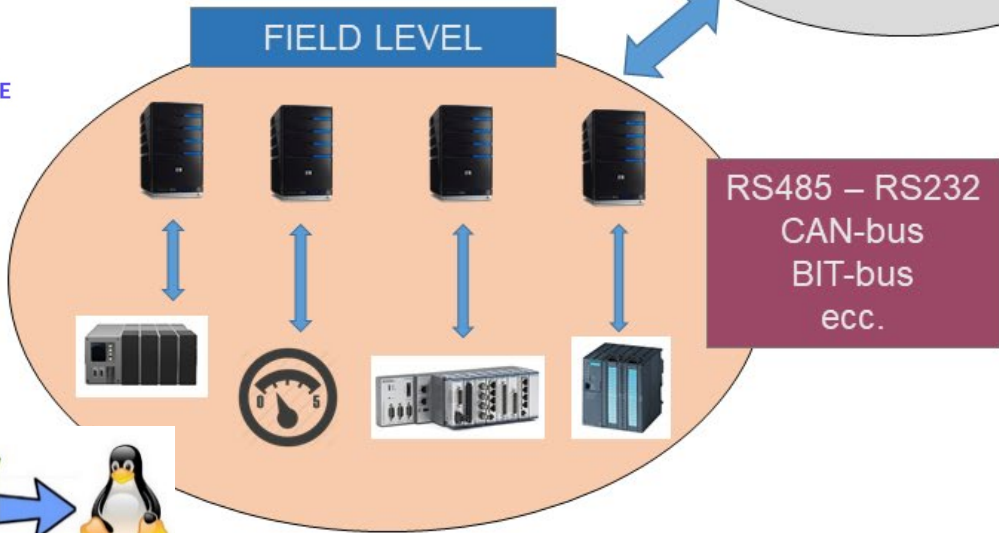
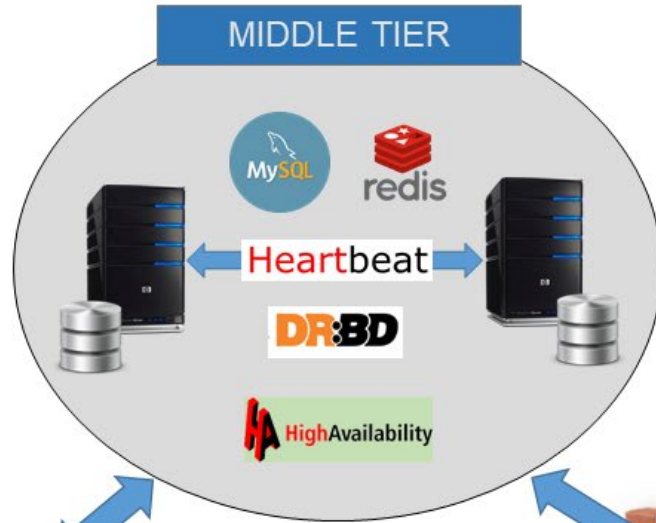
The new Control System Architecture

Transition to more interconnected and smarter devices



PREDICTIVE MAINTENANCE

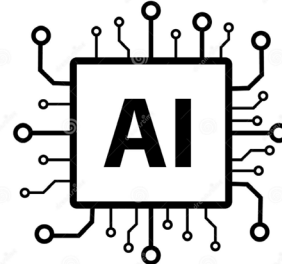
The upgrade of control system is in progress. It will permit a more efficient use of resources, minimizing errors and troubles



Ethernet



USER INTERFACES



Conclusion & Perspectives

- *Several infrastructures that have been for years the focus of the LNS Accelerator Division activities (CS, Tandem, Sources) are suffering from their years, a deep maintenance and development activity is in progress to ensure their use for a time frame comparable to that passed.*
- *Extraordinary maintenance activities are planned for the Tandem and a new control system will be realized, to be integrated in the accelerator management platform. The restart of Tandem operation is expected for end of 2023.*
- *The upgrade of the superconducting source SERSE is a key factor for the production of the beam intensities required by the Cyclotron. The CAESAR source is not able to produce these intensities and taking into account that both sources were conceived in the mid-90s it is important to start the study of a 3rd Generation source to replace them.*
- *The cyclotron upgrading works represents the core of the LNS Accelerator Division activities since most of the CS ancillary equipment will be upgraded (more details in M. Musumeci talk).*